

Hall A

Section 1.



# Fundamental processes in low-temperature plasma: low and high pressure discharges, near-electrode phenomena, radiation, ultrafast processes, diagnostics.

9.00-10.25		Oral Session (OS-1-5).	Chairman: <i>Ilya L. Muzyukin</i>
1	Invited report 9.00-9.25	<b>OES of nitrogen atoms concentration during plasma processing</b> <u>Svetlana V. Avtaeva</u> Institute of Laser Physics SB RAS, Novosibirsk, Russia	
2	Oral 9.25-9.45	<b>Spatial spectroscopy of magnetron discharge argon plasma using a radiative-collisional model</b> <u>Sergey Serushkin</u> Bauman Moscow State Technical University, Moscow, Russia	
3	Oral 9.45-10.05	<b>OES investigation of a low-pressure non-self-sustained glow discharge plasma in Ar:N<sub>2</sub> gas mixture</b> <u>Sergey S. Kovalsky, V.V. Denisov, E.V. Ostroverkhov, V.E. Prokop'ev</u> Institute of High Current Electronics SB RAS, Tomsk, Russia	
4	Oral 10.05-10.25	<b>Magnetic field influence on the penning discharge characteristics</b> <u>Nikita V. Mamedov, A.S. Rohmanenkov, A.A. Solodovnikov</u> Dukhov Automatics Research Institute, Moscow, Russia	

**10.40-12.00**

Oral Session (OS-1-6).

Chairman: *Dmitry A. Sorokin*

1	Oral <b>10.40-11.05</b>	<b>Methods for introducing negative feedback for beam current control in sources with a plasma cathode based on a low pressure arc</b> <u>Maxim Vorobyov, P. Moskvin, V. Devyatkov, N. Koval, V. Shin</u> Institute of High Current Electronics SB RAS, Tomsk, Russia
2	Oral <b>11.05-11.30</b>	<b>The problem of "anomalous" ion transport in high-current vacuum discharges</b> <u>V. Y. Kozhevnikov, Alexandr Kokovin, A. V. Kozyrev</u> Institute of High Current Electronics SB RAS, Tomsk, Russia
3	Oral <b>11.30-11.55</b>	<b>The measurements of vacuum arc behavior at threshold currents</b> <u>Ilya L. Muzyukin, P.S. Mikhailov</u> Institute of Electrophysics UB RAS, Ekaterinburg, Russia

**12.00-12.30**

Closing Ceremony

September 10 (Friday)

## Hall B

### Section 2.



# Gas-discharge methods for surface modification and coating deposition: surface modification, ion implantation, combined methods of surface treatment.

09.00-10.25	Oral Session (OS-2-6).	Chairman: Grey Sh. Boltachev
-------------	------------------------	------------------------------

1	Invited report Online <b>9.00-9.35</b>	<b>Aerosol assisted atmospheric pressure plasma deposition for silver-containing antibacterial coatings</b> <u>Lei Wang, C. Lo Porto, F. Palumbo, M. Modic, U. Cvelbar, C. Leys, A. Nikiforov</u> National University of Defense Technology, Changsha, China
2	Oral <b>9.35-10.00</b>	<b>Plasma modification of the surface of a steel product using the MAK-10 installation</b> <u>S.A. Il'inyh, S.A. Ahmetshin, V.A. Krashaninin, Boris R. Gelchinski, A.A. Rempel</u> Institute of Metallurgy of the Ural Branch of the Russian Academy of Sciences, Ekaterinburg, Russia
3	Oral <b>10.00-10.25</b>	<b>Development of the computer model of the plasma installation</b> <u>Roman A. Okulov, E.V. Popov, B.R. Gelchinski, A.A. Rempel</u> Institute of Metallurgy of the Ural Branch of the Russian Academy of Sciences, Ekaterinburg, Russia